



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Pan et al.

Serial No.: 09/073,494

Filed: May 6, 1998

For: TECHNIQUE FOR ELIMINATION
OF PITTING ON SILICON SUBSTRATE
DURING GATE STACK ETCH

Confirmation No.: 9834

Examiner: H. Vu

Group Art Unit: 2811

Attorney Docket No.: 2915.1US
(96-149.01)

CERTIFICATE OF MAILING

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1.8(a)(1)(ii)

Amanda Holland

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AMENDMENT

Commissioner for Patents
Washington, D.C. 20231

Sir:

The following amendments and remarks are filed in response to the Examiner's remarks in the Office Action mailed October 24, 2002, the three-month shortened statutory period for response to which expired on January 24, 2003. Enclosed herewith is a Petition for One-Month Extension of Time and accompanying fee under 37 C.F.R. § 1.17(a)(1).

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